

# **Analysis of Fluorocarbon Plasma Damage on Si and Its Influence on Ti Silicidation**

Tezuka Y, Kitano N, Nakano N.

Journal of the Electrochemical Society

1995; 142(10):3569-3573

## **ARTICLE IDENTIFIERS**

DOI: 10.1149/1.2050024

PMID: unavailable

PMCID: not available

## **JOURNAL IDENTIFIERS**

LCCN: not available

pISSN: 0013-4651

eISSN: not available

OCLC ID: not available

CONS ID: not available

US National Library of Medicine ID: not available

This article was identified from a query of the SafetyLit database.